

FIG. 2

Title: MOCVD PROCESS USING OZONE AS A REACTANT TO
DEPOSIT A METAL OXIDE BARRIER LAYER

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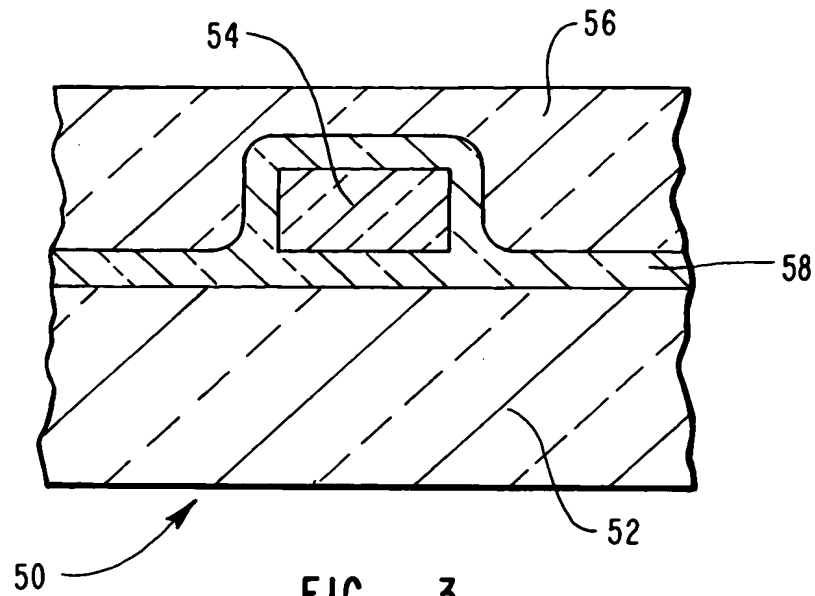


FIG. 3

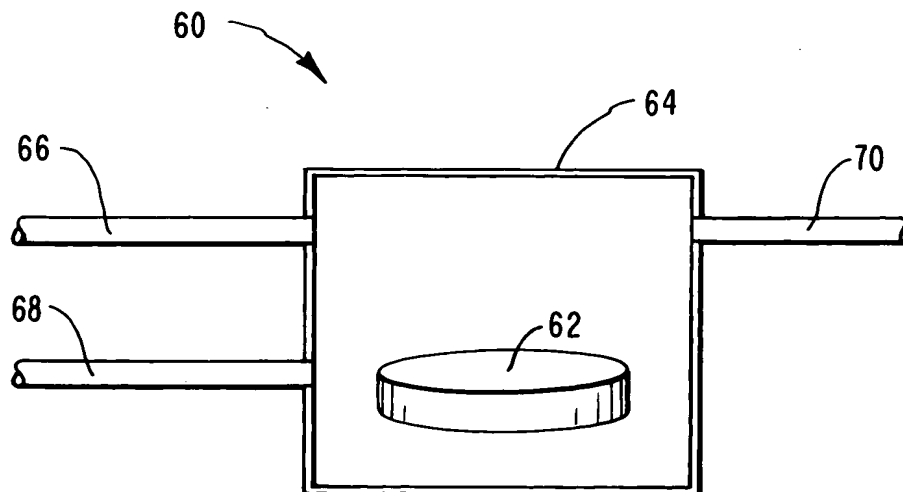


FIG. 4